

**PELLICLE FILM, PELLICLE FRAME BODY, PELLICLE, AND
METHOD FOR PRODUCING THE SAME**

ABSTRACT

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Provided is a pellicle film, a pellicle frame and a pellicle for EUV decreased in the amount of dust or the like attached thereto, and a method for producing the same. Provided is a method for producing a pellicle including forming a pellicle film (202) above a substrate (200); forming a metal mask (204)
10 on a surface of the substrate opposite to a surface having the pellicle film formed thereon; removing a part of the substrate from the side of the metal mask; and removing the metal mask. In an embodiment, the present invention provides a pellicle film, a pellicle frame and a pellicle for EUV decreased in the amount of dust or the like attached thereto, and a method for producing the same.

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Fig. 2